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## CERAMIC HEATER WITH ELECTROSTATIC CHUCK

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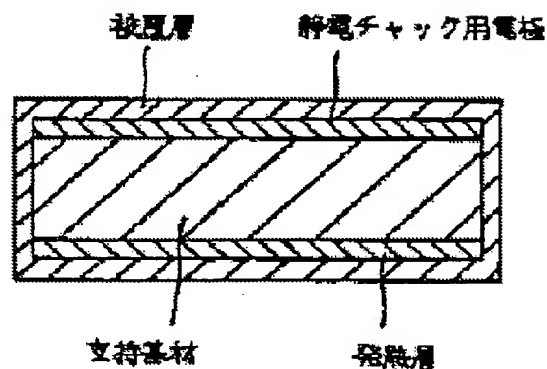
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## Abstract of JP7307377

**PURPOSE:** To provide a ceramic heater with an electrostatic chuck of a structure, wherein even if the heater is used for temperature rise and drop processes in a semiconductor process, separation is not caused in the bonded part of the surface of a support substrate to an electrostatic chuck use electrode and the bonded part of the rear of the support substrate to a heating layer.

**CONSTITUTION:** In a ceramic heater with an electrostatic chuck formed into a structure, wherein an electrostatic chuck use electrode, which consists of conductive ceramics, is bonded on the surface of a support substrate consisting of electrically insulative ceramics and at the same time, a heating layer consisting of conductive ceramics is bonded on the rear of the support substrate and a coating layer consisting of electrically insulative ceramics is provided on the electrode and the heating layer, the surface roughnesses  $R_{max}$  of the support substrate, the electrostatic chuck use electrode and said heating layer are equally set in a surface roughness of 5 $\mu$ m or more.



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